

# Hajime Fujikura

## List of Publications by Year in descending order

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28  
papers

531  
citations

567281

15  
h-index

642732

23  
g-index

28  
all docs

28  
docs citations

28  
times ranked

383  
citing authors

#	ARTICLE	IF	CITATIONS
1	Hydride-vapor-phase epitaxial growth of highly pure GaN layers with smooth as-grown surfaces on freestanding GaN substrates. Japanese Journal of Applied Physics, 2017, 56, 085503.	1.5	74
2	Homo-epitaxial growth of n-GaN layers free from carbon-induced mobility collapse and off-angle-dependent doping variation by quartz-free hydride vapor phase epitaxy. Applied Physics Letters, 2020, 117, .	3.3	42
3	Deep-level transient spectroscopy studies of electron and hole traps in n-type GaN homoepitaxial layers grown by quartz-free hydride-vapor-phase epitaxy. Applied Physics Letters, 2019, 115, .	3.3	37
4	Fabrication of InGaAs Quantum Wires and Dots by Selective Molecular Beam Epitaxial Growth on Various Mesa-Patterned (001)InP Substrates. Japanese Journal of Applied Physics, 1997, 36, 1763-1769.	1.5	33
5	Molecular-Beam Epitaxy and Device Applications of III-V Semiconductor Nanowires. MRS Bulletin, 1999, 24, 25-30.	3.5	32
6	Macrodefect-free, large, and thick GaN bulk crystals for high-quality 2â€“6 in. GaN substrates by hydride vapor phase epitaxy with hardness control. Japanese Journal of Applied Physics, 2018, 57, 065502.	1.5	32
7	Elimination of macrostep-induced current flow nonuniformity in vertical GaN PN diode using carbon-free drift layer grown by hydride vapor phase epitaxy. Applied Physics Express, 2018, 11, 045502.	2.4	26
8	Recent progress of high-quality GaN substrates by HVPE method. Proceedings of SPIE, 2017, , .	0.8	25
9	Roughening of GaN homoepitaxial surfaces due to step meandering and bunching instabilities and their suppression in hydride vapor phase epitaxy. Applied Physics Letters, 2018, 113, .	3.3	23
10	Surface passivation of In <sub>0.53</sub> Ga <sub>0.47</sub> As ridge quantum wires using silicon interface control layers. Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena, 1996, 14, 2888.	1.6	22
11	Reappraisal of Si-Interlayer-Induced Change of Band Discontinuity at GaAs-AlAs Heterointerface Taking Account of Delta-Doping. Japanese Journal of Applied Physics, 1992, 31, L1012-L1014.	1.5	21
12	Roles of carbon impurities and intrinsic nonradiative recombination centers on the carrier recombination processes of GaN crystals. Applied Physics Express, 2020, 13, 012004.	2.4	20
13	Realization of Low Dislocation GaN/Sapphire Wafers by 3-Step Metalorganic Vapor Phase Epitaxial Growth with Island Induced Dislocation Control. Japanese Journal of Applied Physics, 2003, 42, 2767-2772.	1.5	19
14	Photoluminescence and Cathodoluminescence Investigation of Optical Properties of InP-Based InGaAs Ridge Quantum Wires Formed by Selective Molecular Beam Epitaxy. Japanese Journal of Applied Physics, 1996, 35, 1333-1339.	1.5	17
15	Formation of device-oriented InGaAs coupled quantum structures by selective MBE growth on patterned InP substrates. Physica E: Low-Dimensional Systems and Nanostructures, 2000, 7, 864-869.	2.7	17
16	Controlled Formation of Narrow and Uniform InP-Based In <sub>0.53</sub> Ga <sub>0.47</sub> As Ridge Quantum Wire Arrays by Selective Molecular Beam Epitaxy. Japanese Journal of Applied Physics, 1998, 37, 1532-1539.	1.5	15
17	Hardness control for improvement of dislocation reduction in HVPE-grown freestanding GaN substrates. Journal of Crystal Growth, 2012, 350, 38-43.	1.5	14
18	Isochronal annealing study of Mg-implanted p-type GaN activated by ultra-high-pressure annealing. Applied Physics Express, 2021, 14, 056501.	2.4	14

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19	Fabrication of InGaAs Wires by Preferential Molecular Beam Epitaxy Growth on Corrugated InP Substrate. Japanese Journal of Applied Physics, 1994, 33, 919-924.	1.5	12
20	Direct formation of InGaAs coupled quantum wire-dot structures by selective molecular beam epitaxy on InP patterned substrates. Solid-State Electronics, 1998, 42, 1413-1417.	1.4	10
21	Interface profile optimization in novel surface passivation scheme for InGaAs nanostructures using Si interface control layer. Journal of Electronic Materials, 1993, 22, 289-295.	2.2	8
22	Fabrication of large flat gallium nitride templates with extremely low dislocation densities in the 106cm <sup>2</sup> range by novel two-side hydride vapor-phase epitaxial growth. Journal of Crystal Growth, 2017, 475, 208-215.	1.5	6
23	Substantial and simultaneous reduction of major electron traps and residual carbon in homoepitaxial GaN layers. Applied Physics Letters, 2021, 118, .	3.3	5
24	Selective molecular beam epitaxy growth of quantum wire-dot coupled structures with novel high index facets for InGaAs single electron transistor arrays. Microelectronics Journal, 1999, 30, 397-401.	2.0	3
25	Control of Dot Size and Tunneling Barrier Profile in In <sub>0.53</sub> Ga <sub>0.47</sub> As Coupled Quantum Wire-Dot Structures Grown by Selective Molecular Beam Epitaxy on Patterned InP Substrates. Japanese Journal of Applied Physics, 1999, 38, 421-424.	1.5	2
26	Scanning tunneling microscopy and spectroscopy study of ultrathin Si interface control layers grown on (001) GaAs for surface passivation. Applied Surface Science, 2000, 159-160, 292-300.	6.1	1
27	Growth of InGaN films on hardness-controlled bulk GaN substrates. Applied Physics Letters, 2019, 115, 172102.	3.3	1
28	Realization of InP-Based InGaAs single electron transistors on wires and dots grown by selective MBE. Microelectronic Engineering, 1999, 47, 201-203.	2.4	0